

KX320 Series

Linton
LINTONCRYSTAL.COM

KX320 Semiconductor MCZ Crystal Growing Furnace



KX320MCZR



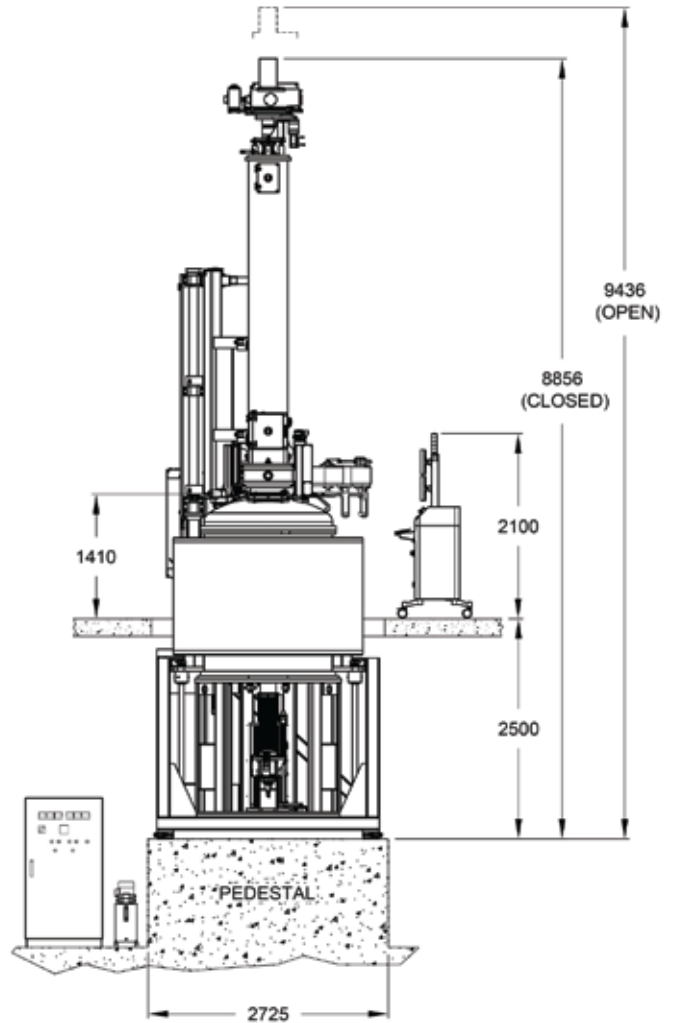
- **OPTIMIZED FOR 300 mm INGOT GROWTH**
- **MAGNET READY**
Resistive Magnet / Superconducting Magnet
- **ADVANCED CONTROL SYSTEM**
- **LOW POWER CONSUMPTION**
- **INTEGRATED COMMUNICATIONS**
with optional WINGS systems
- **CUSTOM CONFIGURATIONS AVAILABLE**



KX320

MCZ CRYSTAL GROWING FURNACE

The KX320MCZR is optimized for producing 300 mm crystals with a 1300 mm furnace size and 3500 mm-high receiving chamber for accommodating 32-inch crucibles and is magnet-ready. Options include resistive and superconducting magnets.



Dimensions shown are typical and can be customized to meet customer requirements

PERFORMANCE

Furnace Chamber Diameter	1300 mm (51.2 in)
Receiving Chamber Height	3500 mm (137.8 in)
Throat Diameter	400 mm (15.7 in)
Seed Lift Rate	0-508 mm/hr
Seed Jog Speed (Nominal)	508 mm/min
Seed Rotation (Reversible)	0-30 rpm
Total Crucible Travel	650mm (25.6 in)
Crucible Lift Rate	0-127 mm/hr
Crucible Jog Speed (Nominal)	127 mm/min
Crucible Rotation (Reversible)	0-30 rpm

SILICON CHARGE CAPACITY

CRUCIBLE DIAMETER*	CHARGE SIZE
32.0 in	up to 440 kg

OPTIONS & ACCESSORIES

Cooling Tube	Cusp Magnet
Feeders	Vacuum Pumps
Hot Zones	Ingot and Crucible Handling
Filters	Maintenance Tools